

ABSTRACT

In a plasma treatment apparatus for performing plasma treatment by accommodating a substrate in a treatment chamber, a fixed guide 12 and a movable guide 13 made of a ceramic are arrayed in an X direction (in a substrate transporting direction) for guiding both side end portions of the substrate held on a ceramic-made mounting plate 10, and both end portions of the movable guide 13 are supported by supporting members. In this construction, these supporting members are fitted to fixed members 15A and 15B arranged in a Y direction with the mounting plate 10 placed therebetween, such that an interval in the Y direction is adjustable. Consequently, the ceramic-made guide member 13 can be mounted and demounted without directly bolting it, and it is possible to prevent the generation of an abnormal discharge by using as objects multiple product thin-type substrates with different widthwise dimensions.